Special Issue

Virtual Measuring Systems and Digital Twins

Message from the Guest Editors

In the course of the digital transformation, the importance of mathematical-physical simulations and in silico experiments is increasing rapidly. If real measuring equipment and measurements are simulated with such simulations, this can be called a "virtual measuring device" or "virtual measurement". In many areas, these are now in everyday use. In this development, the task of metrology is to secure confidence in simulation results when they are used in the same way as or combined with real measurements. From the point of view of metrology, this results in several overriding questions:

- How to ensure confidence in simulation results
- How to establish comparability of virtual and real measurements
- Which standards for interfaces, metadata and data formats are necessary

This Special Issue is related to the VirtMet Workshop 2021. In addition to VirtMet Workshop 2021 papers, other independent submissions are also welcome.

Guest Editors

Dr. Sascha Eichstädt

Prof. Dr. Markus Bär

Dr. Karin Kniel

Deadline for manuscript submissions

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Metrology Editorial Office MDPI, Grosspeteranlage 5 4052 Basel, Switzerland Tel: +41 61 683 77 34 metrology@mdpi.com

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Message from the Editor-in-Chief

Metrology draws together researchers from diverse areas of metrology or measurement technology in a wide variety of applications. I encourage you to submit your manuscripts for consideration or publication in the area of measurement engineering, according to the scope of the journal. Metrology is supported by our authors and their institutes through low article processing charges (APC) for accepted papers. We hope you will support the journal by becoming one of our authors.

Editor-in-Chief

Prof. Dr. Han Haitjema

Department of Mechanical Engineering, KU Leuven, Celestijnenlaan 300, 3001 Leuven, Belgium

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